

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	1	("20040190579").PN.	US-PGPUB; USPAT	OR	OFF	2006/01/24 14:29
S2	78	((Hayashibe near2 Kazuya) or (Morita near2 Masayuki) or (Fukui near2 Tatsuo) or (Imai near3 Yutaka)).in.	US-PGPUB; USPAT	AND	ON	2006/01/24 14:31
S3	710	((Hayashibe near2 Kazuya) or (Morita near2 Masayuki) or (Fukui near2 Tatsuo) or (Imai near3 Yutaka)).in.	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/24 14:42
S6	13	S2 and laser and (mirror\$1 or reflect\$3) and substrate	US-PGPUB; USPAT	AND	ON	2006/01/24 14:43
S4	2	((Hayashibe near2 Kazuya) or (Morita near2 Masayuki) or (Fukui near2 Tatsuo) or (Imai near3 Yutaka)).in. and laser and (mirror\$1 or reflect\$3) and substrate	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/24 14:43
S7	1824	(second near2 substrate) and (mirror\$1 or reflect\$3) and ((concave or curv\$5) near3 substrate)	US-PGPUB; USPAT	AND	ON	2006/01/24 14:46
S8	2726	(second near2 substrate) and (mirror\$1 or reflect\$3) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate)	US-PGPUB; USPAT	AND	ON	2006/01/24 15:01
S9	2726	(second near2 substrate) and (mirror\$1 or reflect\$3) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate)	US-PGPUB; USPAT	AND	ON	2006/01/24 15:05
S11	2280	(second near2 (wafer or substrate)) and "372"/\$	US-PGPUB; USPAT	AND	ON	2006/01/24 15:06
S14	1	("20020122308").PN.	US-PGPUB; USPAT	OR	OFF	2006/01/24 15:30
S13	44	(second near2 (wafer or substrate)) and (mirror\$1 or reflect\$3) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and "372"/\$.cccls.	US-PGPUB; USPAT	AND	ON	2006/01/24 15:30
S10	2802	(second near2 (wafer or substrate)) and (mirror\$1 or reflect\$3) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate)	US-PGPUB; USPAT	AND	ON	2006/01/24 15:32
S16	81	(second near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 second) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 mirror)	US-PGPUB; USPAT	AND	ON	2006/01/25 07:16
S18	0	(second near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 (mirror\$1 or reflect\$3))	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/25 07:19
S15	524	(second near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 second) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate)	US-PGPUB; USPAT	AND	ON	2006/01/25 08:08
S20	86	S19 not S17	US-PGPUB; USPAT	AND	ON	2006/01/25 08:10
S19	214	(second near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near2 (mirror\$1 or reflect\$3))	US-PGPUB; USPAT	AND	ON	2006/01/25 08:10
S21	70	(flat near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 (mirror\$1 or reflect\$3))	US-PGPUB; USPAT	AND	ON	2006/01/25 08:17
S17	128	(second near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 (mirror\$1 or reflect\$3))	US-PGPUB; USPAT	AND	ON	2006/01/25 08:17
S25	1	S23 and (solid near2 state near1 laser)	US-PGPUB; USPAT	AND	ON	2006/01/25 08:43
S24	15	S23 and laser	US-PGPUB; USPAT	AND	ON	2006/01/25 08:43

S22	44	((flat near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)))	US-PGPUB; USPAT	AND	ON	2006/01/25 08:56
S27	47	((flat near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and ((concave or curv\$5 or arc\$4 or bent or round\$2) near3 substrate) and (concave near2 (mirror\$1 or reflect\$3 or element or device or system)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)))	US-PGPUB; USPAT	AND	ON	2006/01/25 08:57
S28	3	S27 not S22	US-PGPUB; USPAT	AND	ON	2006/01/25 09:35
S23	26	((flat near2 (wafer or substrate)) and ((mirror\$1 or reflect\$3) near2 (flat or plan\$3)) and (concave near2 substrate) and (concave near2 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)))	US-PGPUB; USPAT	AND	ON	2006/01/25 10:18
S31	3	((mirror\$1 or reflect\$3) near1 (flat or plan\$3)) and (concave near1 substrate) and (concave near1 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near1 (substrate or wafer)) and laser	US-PGPUB; USPAT	AND	ON	2006/01/25 10:32
S30	159	((mirror\$1 or reflect\$3) near3 (flat or plan\$3)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer))	US-PGPUB; USPAT	AND	ON	2006/01/25 10:32
S29	11	((mirror\$1 or reflect\$3) near1 (flat or plan\$3)) and (concave near1 substrate) and (concave near1 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near1 (substrate or wafer))	US-PGPUB; USPAT	AND	ON	2006/01/25 10:32
S33	60	((mirror\$1 or reflect\$3) near3 (flat or plan\$3)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)) and laser and ((flat or plane) near3 (substrate or wafer))	US-PGPUB; USPAT	AND	ON	2006/01/25 10:38
S34	27	S32 not S33	US-PGPUB; USPAT	AND	ON	2006/01/25 10:39
S32	87	((mirror\$1 or reflect\$3) near3 (flat or plan\$3)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)) and laser	US-PGPUB; USPAT	AND	ON	2006/01/25 11:04
S36	3	("4776868" "5504302" "5871653").PN. OR ("6632375").URPN.	US-PGPUB; USPAT; USOCR	AND	ON	2006/01/25 11:26
S35	103	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)) and laser	US-PGPUB; USPAT	AND	ON	2006/01/25 11:29
S38	3	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer))	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/25 11:30
S37	202	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer))	US-PGPUB; USPAT	AND	ON	2006/01/27 10:12
L3	143	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)) and (laser or semiconductor)	US-PGPUB; USPAT	AND	ON	2006/01/27 10:13
L5	480	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) with ((second or upper or lower or top or bottom) near2 (substrate or wafer)) with (laser))	US-PGPUB; USPAT	AND	ON	2006/01/27 10:35
L4	103	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or bottom)) and (concave near3 substrate) and (concave near3 (mirror\$1 or reflect\$3)) and ((second or upper or lower or top or bottom) near2 (substrate or wafer)) and (laser)	US-PGPUB; USPAT	AND	ON	2006/01/27 10:35

L7	34	((mirror\$1 or reflect\$3) near1 (second or upper or lower or top or botton)) with ((second or upper or lower or top or botton) near1 (substrate or wafer)) with (laser))	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/27 10:36
L6	141	((mirror\$1 or reflect\$3) near3 (second or upper or lower or top or botton)) with ((second or upper or lower or top or botton) near2 (substrate or wafer)) with (laser))	USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2006/01/27 10:36
L9	4	((mirror\$1 or reflect\$3) near1 (second or upper or lower or top or botton)) with ((second or upper or lower or top or botton) near1 (substrate or wafer)) with (laser)) and (free near3 spectral near3 range)	US-PGPUB; USPAT	AND	ON	2006/01/27 10:38
L10	78	((mirror\$1 or reflect\$3) near1 (second or upper or lower or top or botton)) with ((second) near1 (substrate or wafer)) with (laser))	US-PGPUB; USPAT	AND	ON	2006/01/27 10:45
L8	150	((mirror\$1 or reflect\$3) near1 (second or upper or lower or top or botton)) with ((second or upper or lower or top or botton) near1 (substrate or wafer)) with (laser))	US-PGPUB; USPAT	AND	ON	2006/01/27 10:45